

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
	)	
<b>Junko OHUCHI et al.</b>	)	<b>Group Art Unit: Not Yet Assigned</b>
	)	
<b>Serial No.: Not Yet Assigned</b>	)	<b>Examiner: Not Yet Assigned</b>
	)	
<b>Filed: November 19, 2003</b>	)	
	)	
<b>For: PLASMA PROCESSING</b>	)	
<b>APPARATUS AND PLASMA</b>	)	
<b>PROCESSING METHOD</b>	)	

**MAIL STOP PATENT APPLICATION**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the documents listed on attached Form PTO-1449. Copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form. This Information Disclosure Statement is being filed with the above-referenced application.

The following is a concise statement of relevance for each of the non-English language documents:

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1. Japanese Patent Publication No. 2002-009050 - discloses an ashing method of resist on an organic low-k dielectric film, which consists of following two process steps: ashing with ionic species in order to suppress to deteriorating the organic low dielectric film as first step, and ashing with plasma induced by microwave as second step. The relevance of this document is also discussed at pages 2-3 of the specification of the present application.

2. Japanese Patent Publication No. 2001-189305 - The relevance of this document is discussed at page 4 of the specification of the present application. This document also corresponds to U.S. Patent No. 6,492,186 also submitted herewith.

Also, an English-language abstract of each non-English language document is enclosed.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

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If there is any fee due in connection with the filing of this Statement, please  
charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
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Dated: November 19, 2003

By: 

Richard V. Burgujian  
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Enclosures  
RVB/FPD/sci

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## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	04329.3179	Serial No.	N t Yet Assigned
Applicants	Junk OHUCHI et al.		
Filing Date	N vember 19, 2003	Group:	N t Yet Assigned

U.S. PATENT DOCUMENTS							
Examiner Initial*		Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriat
		6,492,186 B1	12/10/02	HAN et al.			

FOREIGN PATENT DOCUMENTS							
		Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
		2001-189305	07/10/01	JAPAN			ABSTRACT
		2002-009050	01/11/02	JAPAN			ABSTRACT

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	

Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce